

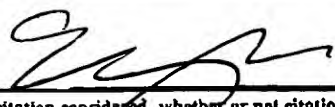
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INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 150.00650102	Serial No.: 09/603,132
	Applicant(s): Vaartstra et al.	Confirmation No.: 3538
	Application Filing Date: June 23, 2000	Group: 2815
	Information Disclosure Statement mailed: May <u>9</u> , 2005	

U.S. PATENT DOCUMENTS

Examiner Initial	Copy Enclosed	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
EL		5,962,716	10/05/99	Uhlenbrock et al.			
EL		6,074,945	06/13/00	Vaartstra et al.			
EL		6,114,557	09/05/00	Uhlenbrock et al.			
EL		6,133,159	10/17/00	Vaartstra et al.			
EL		6,197,628	03/06/01	Vaartstra et al.			
EL		6,204,172	03/20/01	Marsh			
EL		6,261,850	07/17/01	Marsh			
EL		6,281,125	08/28/01	Vaartstra et al.			
EL		6,284,655	09/04/01	Marsh			
EL		6,323,081	11/27/01	Marsh			
EL		6,323,511	11/27/01	Marsh			
EL		6,403,414	06/11/02	Marsh			
EL		6,429,127	08/06/02	Derderian et al.			
EL		6,455,423	09/24/02	Marsh			
EL		6,495,458	12/17/02	Marsh			
EL		6,576,778	06/10/03	Uhlenbrock et al.			
EL		6,784,504	08/31/04	Derderian et al.			
EL		6,872,420	03/29/05	Uhlenbrock et al.			
EL		2002/0008270	01/24/02	Marsh			
EL		2002/0058415	05/16/02	Derderian et al.			

EXAMINER 	Date Considered 7/14/05
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OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

Examiner Initial	Copy Enclosed	Document Description
CL	X	Wolf and Tauber, "Refractory Metals and Their Silicides in VLSI Fabrication," <i>Silicon Processing for the VLSI Era Volume 1: Process Technology</i> , Sunset Beach, California, 1986:384-393.
CL	X	Yang, "Types of Thin Film," <i>Thin Film Process</i> . [online]. [retrieved on 2005-05-03] from the Internet. Retrieved from the Internet:<URL:http://www-yiy.me.ntu.edu.tw/IC/6p.pdf: 11 pgs.

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